

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Inventors: Wei Gao, and Yoshi Ono

Serial No: Not Yet Assigned

Filed: Herewith

Title: METHOD OF DEPOSITING A
CONDUCTIVE NIOBIUM
MONOXIDE FILM FOR MOSFET
GATES

PATENT APPLICATION

Attorney Docket No.
SLA0782

Hon. Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97


Sir:

Listed on attached Form PTO-1449 is information submitted pursuant to
37 C.F.R. §1.56. A copy of each listed publication is submitted herewith.

Applicant respectfully requests that the listed information be considered by
the Examiner and made of record in the above-identified application.

September 30, 2003
(Date)

Respectfully submitted,



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